

Seebeck Enhancement via Quantum Confinement in MOSFET's: Towards Monolithic On-Chip Cooling

SAND2016-1224C

Key Team Members:

PI:

- Ihab El-Kady

Design & Experimental Measurements:

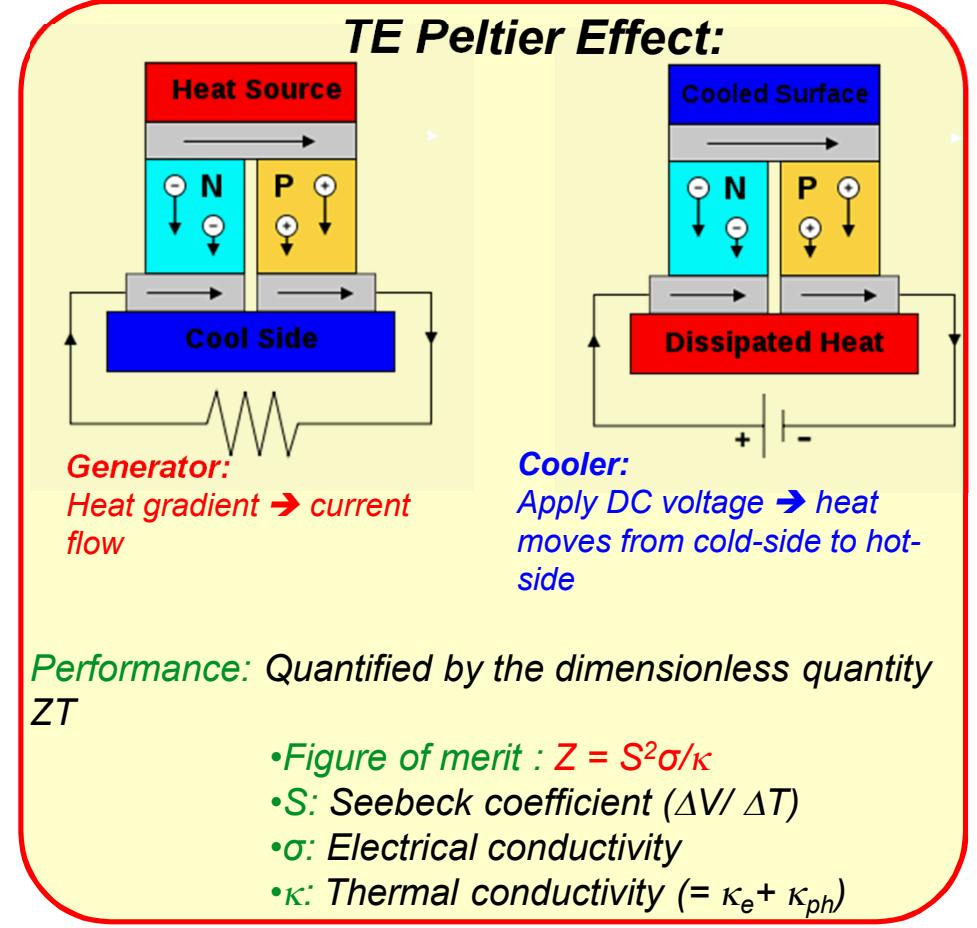
- Charles Reinke (Probe Station)
- Brian Swartzentruber (Cryostat)
- Aaron Katzenmeyer (Post Doc.)

Transport Theory:

- Erik Nielsen

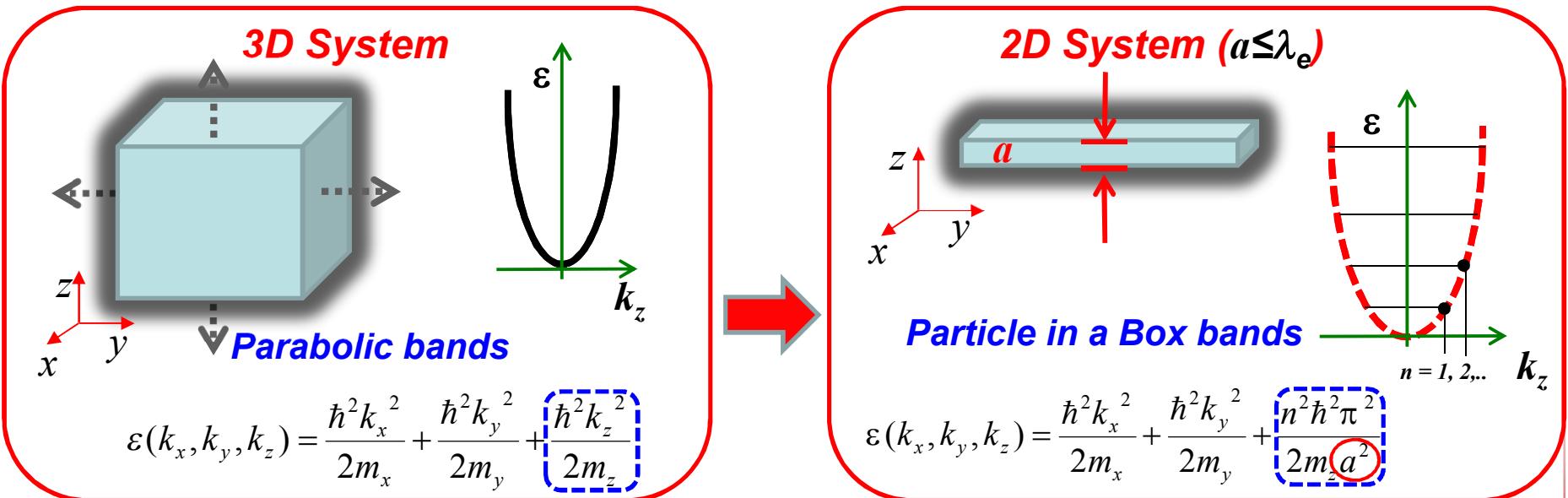
Fabrication:

- Tom Hill (STD. MOSFET-Fab)



Objective: Increasing S via Quantum Confinement

- According to the Mott^{1,2} and Wood³ \Rightarrow Thermodynamically $S \propto$ Entropy per carrier
- Hicks and Dresselhous^{4,5} \Rightarrow Reduced dimensionality \Rightarrow Increase the Entropy share of each carrier



- Following the derivation of the thermoelectric transport coefficients^{4,5}:

$$S_{3D} = -\frac{k_B}{e} \left(\frac{5F_{\frac{3}{2}}(\mu)}{3F_{\frac{1}{2}}(\mu)} - \frac{\mu}{k_B T} \right)$$

Electronic contribution to S

$$S_{2D} = -\frac{k_B}{e} \left(\frac{2F_1(\mu)}{F_0(\mu)} - \frac{\mu}{k_B T} + \frac{n^2 \hbar^2 \pi^2}{2m_z a^2 k_B T} \right)$$

Electrochem. contribution to S

Effect of quantized dimension

Reduced order by $\frac{1}{2}$ due to quantized missing dimension

Thermodynamics:

$$dU = TdS - PdV + \sum_i \mu_i dN_i$$

$$TdS = dU - \sum_i \mu_i dN_i$$

$$S \leftrightarrow \text{Entropy / carrier}$$

- $F_i(\mu)$: Is the Fermi-Dirac Distribution function
- μ : is the Chemical potential

Creation of a 2D quantum system:

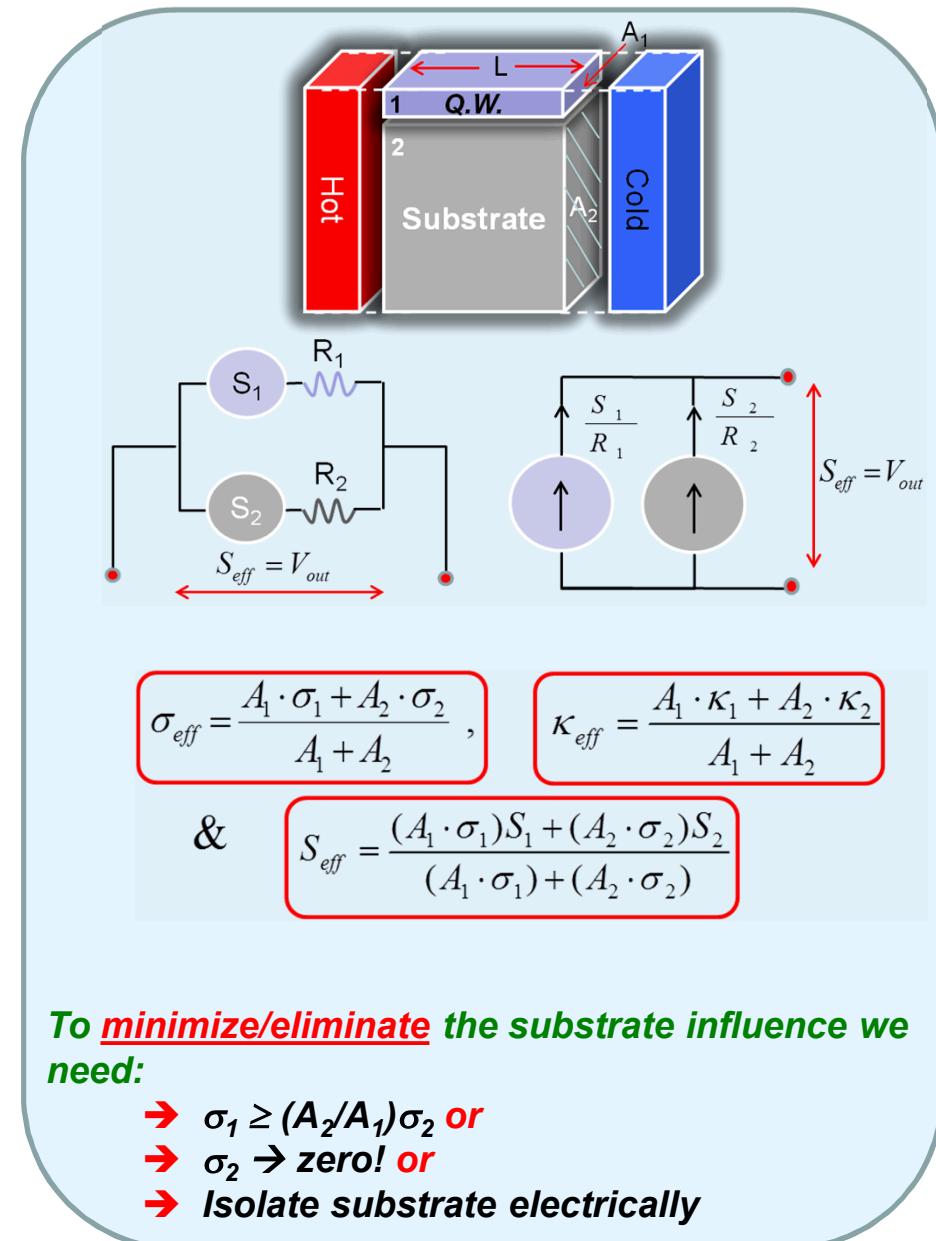
1. Traditionally done by ALD → “nm” layer thicknesses → Superlattices
 - Difficult to integrate
 - Hard to scale-up
 - We will create a 2D electronic QW at the top layer of a 3D slab by using an electric field

Eliminating the substrate effects:

2. Because we will now have a “substrate”
 - Substrate will compete with our QW for transport!
 - Rather than eliminate the substrate → we will isolate it electrically to reduce its influence

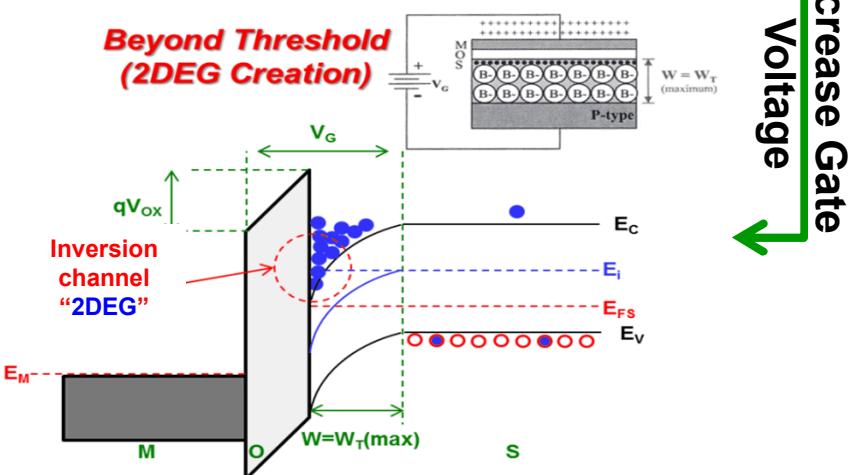
Practicality Challenge:

3. How much energy can we move through the QW as oppose to the substrate?
 - Force enough of the energy to move though the QW
 - Calculate performance metrics
 - Evaluate potential integration schemes



MOS Capacitor Under Inversion

Beyond Threshold (2DEG Creation)



Is the inversion channel narrow enough?

Book Chapter preprint, C. Hu

5.9 • Inversion and Accumulation Charge-layer Thickness

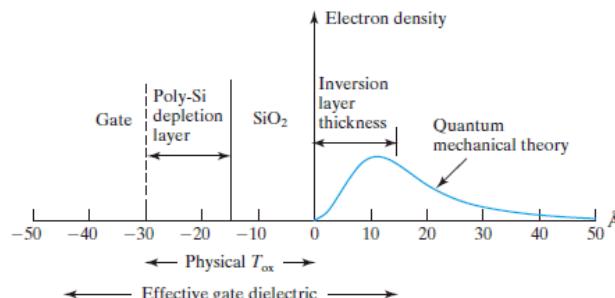


FIGURE 5-24 Average location of the inversion-layer electrons is about 15 Å below the Si-SiO₂ interface. Poly-Si gate depletion is also shown.

⁸ Yang, K., Y-C. King, C. Hu, Technical Digest of Symposium on VLSI Technologies, p.77-78, (1999)

¹⁰ IEEE TRANSACTIONS ON ELECTRON DEVICES, VOL. 44, NO. 11, NOVEMBER 1997

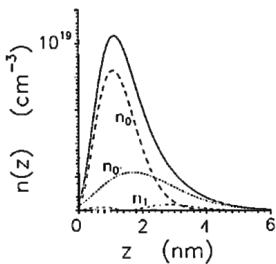


Fig. 1. Total electron concentration as a function of the distance from the silicon-SiO₂ interface (solid line) and electron concentrations contained in the three lowest subbands (dashed lines). Long dashed lines correspond to the two ellipsoids perpendicular to the interface in a transistor with a (100)-oriented substrate. Short dashed lines correspond to the four parallel ellipsoids. Doping concentration: $5 \cdot 10^{17} \text{ cm}^{-3}$. Electron density per unit area: 10^{12} cm^{-2} .

⁹ Andreas Wettstein, "Quantum Effects in MOS devices", (2000)

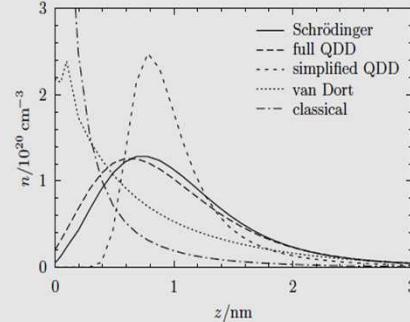


Figure 5.4.: Density distribution in the device of Fig. 5.2 in deep inversion ($U_g = 4 \text{ V}$)

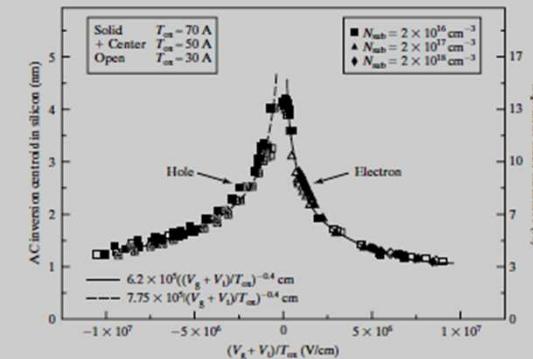
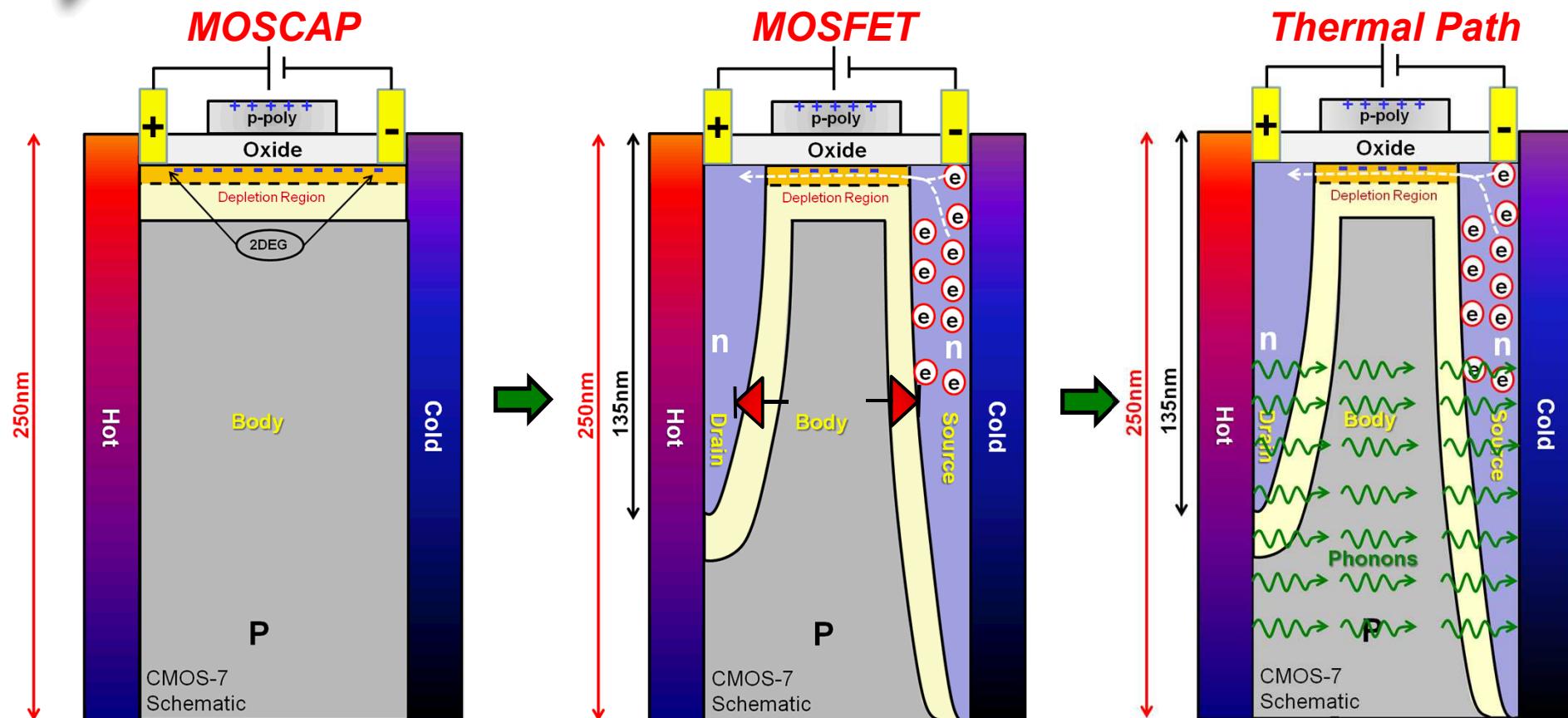


FIGURE 5-25 Average inversion-layer thickness (centroid) for electrons (in P body) and holes (in N body). (From [3]. © 1999 IEEE.)

- **SiGe-NW 11-25nm (2DHG defined by gate voltage): increase in S with increasing gate voltage** [¹¹ Jaeyun Moon, et. al., Nano Lett., dx.doi.org/10.1021/nl304619u (2013)]

Eliminating the substrate effect via MOSFET structure

Delaminating the Electrical and Thermal paths



**The most likely electric path
is through 2DEG
Body still competes**

**The only possible electric
path is through 2DEG
Body electrically isolated**

**Dominant thermal
path will be through
the body**

$$S_{eff} \approx S_{2DEG}, \quad \sigma_{eff} \approx \sigma_{2DEG} \quad \& \quad \kappa_{eff} \approx \kappa_{Body}$$

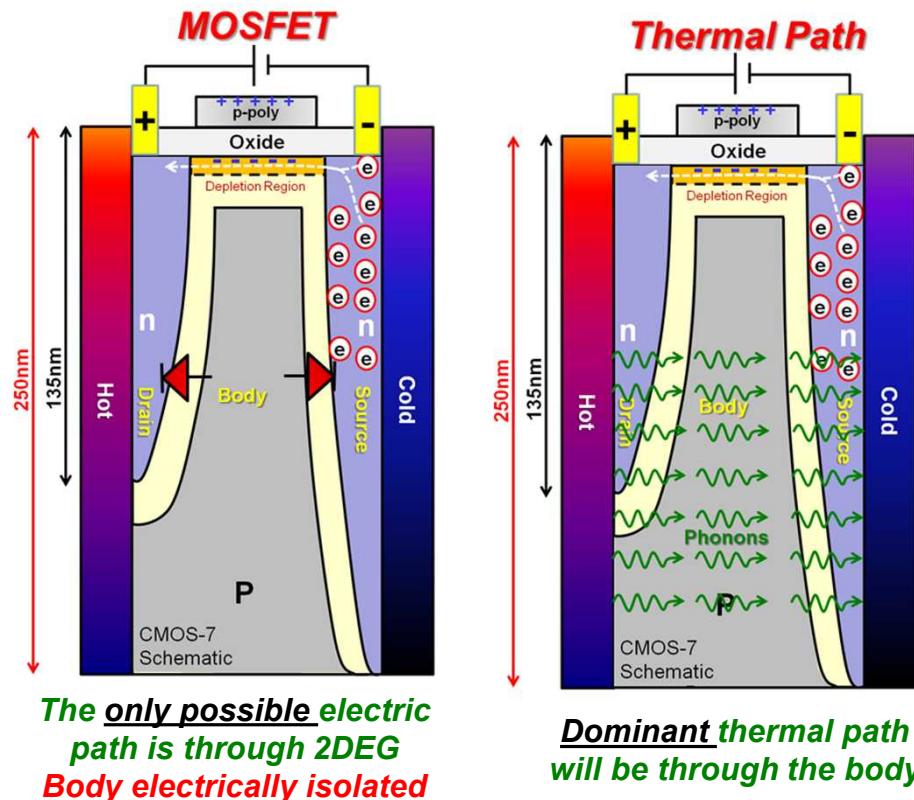
Our Approach: *Electronic as opposed to Physical Confinement*

Creation of a 2D quantum system:

1. Traditionally a physically thin layer: (e.g. "nm" Superlattices, Graphene, ...etc.)
- Difficult to handle, integrate and scale-up
- We will create a 2D electronic QW at the top layer of a 3D slab by using an electric field

Minimizing the substrate effects:

2. Because we will now have a "substrate"
- Substrate will compete with our QW for transport!
- Rather than eliminate the substrate → we will isolate it electrically to reduce its influence

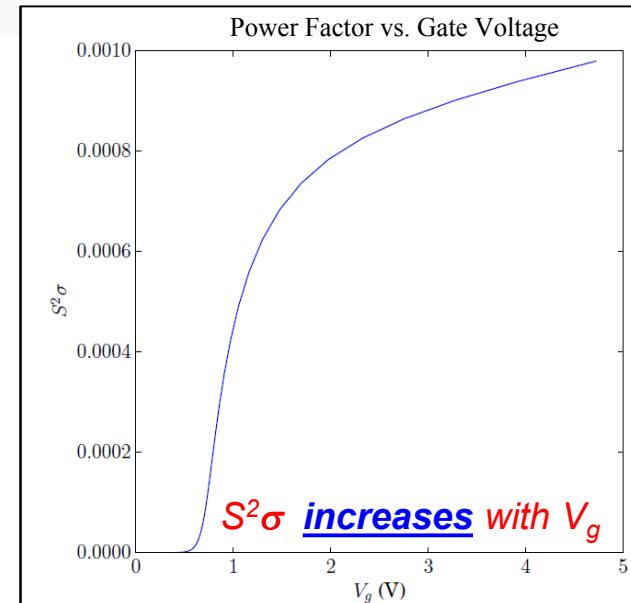
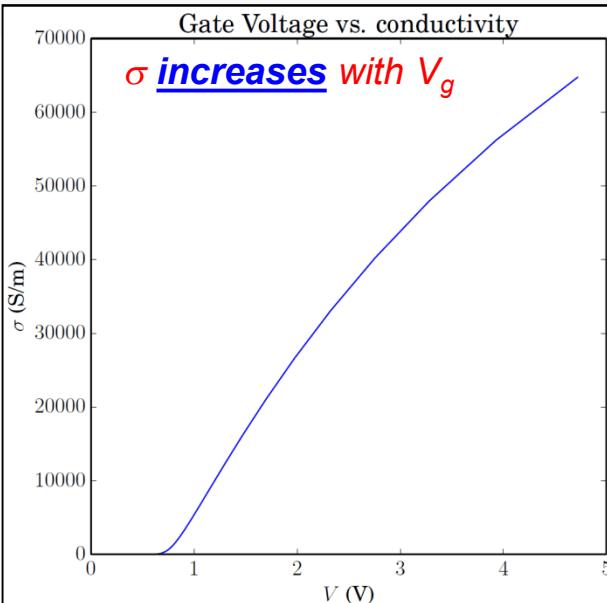
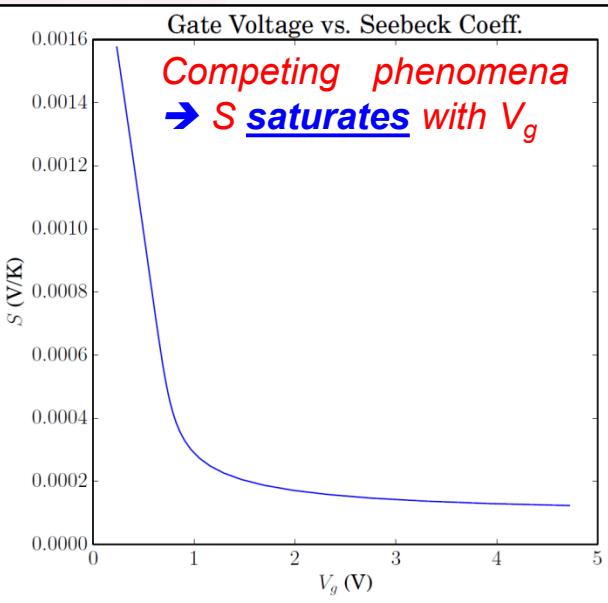


$$S_{eff} \approx S_{2DEG}, \quad \sigma_{eff} \approx \sigma_{2DEG} \quad \& \quad \kappa_{eff} \approx \kappa_{Body}$$

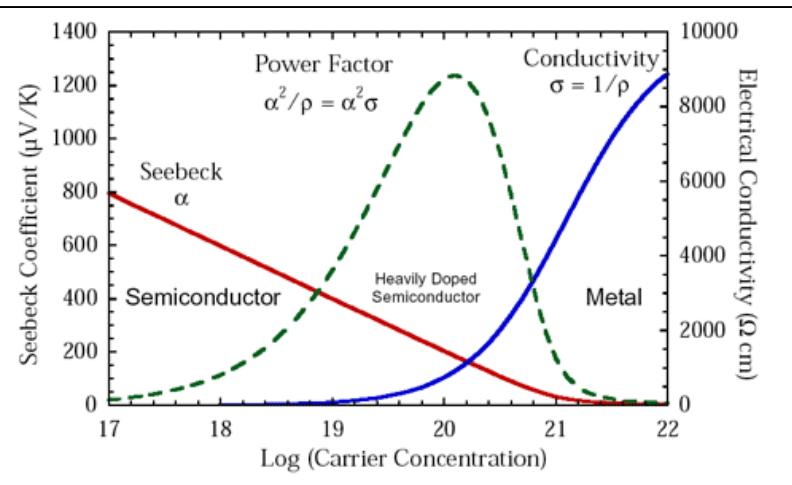
Quantum Confinement Effects-Theoretical Predictions

Quantum versus Classical TE Behavior

Predicted Behavior



Classical Behavior



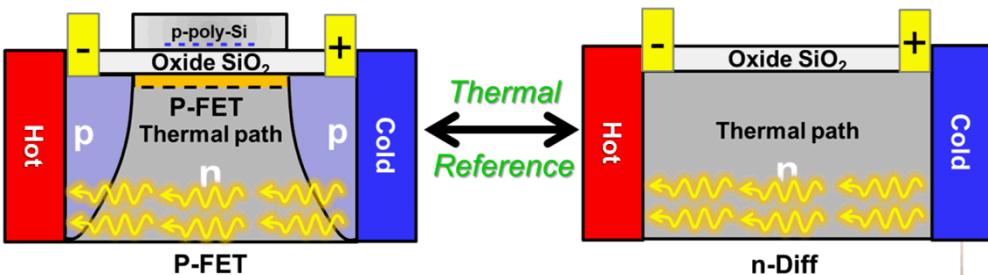
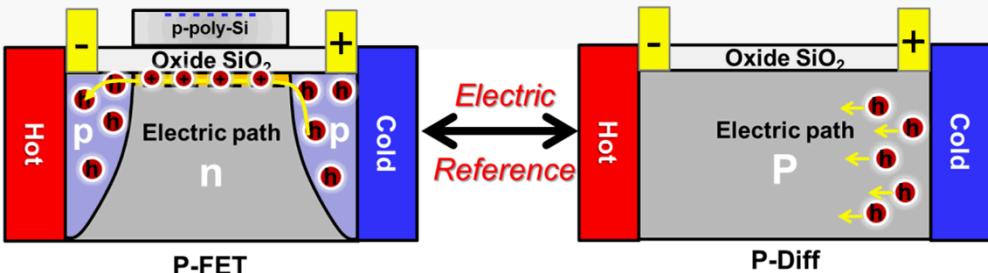
- Recall that $V_g \propto N$ (carrier concentration)
- Given:
 - Enhancement in channel conductivity compared to body
 - Size of channel
 - Carrier concentration in the FET channel $>> 10^{21} \text{ cm}^{-3}$!
- Expected behavior is non-classical!

Experimental Measurements

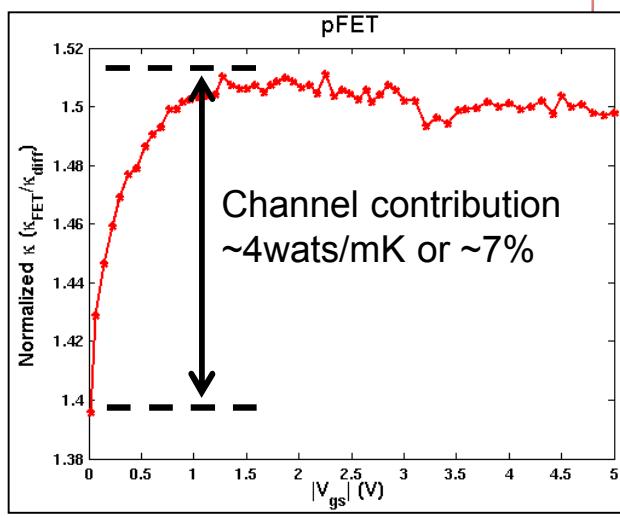
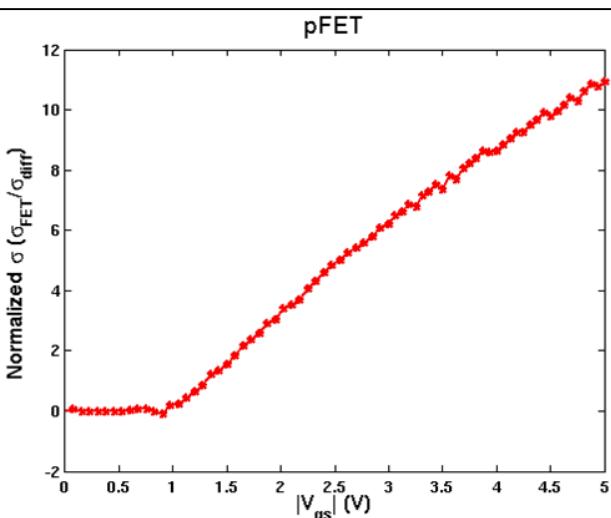
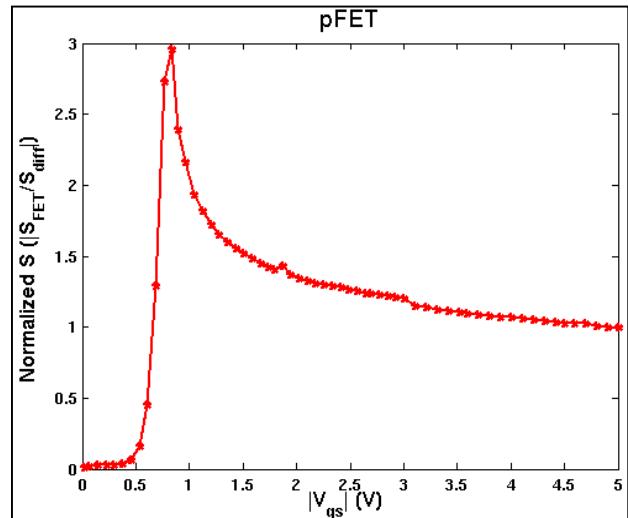
P-MOSFET MPW111102E-W01

To avoid any systematic errors:

- Normalize electric measurements (σ & S)
- Intrinsic properties independent of size
- p-FET to p-diffusion
 - Doping determines threshold voltage (channel formation)
 - Channel characteristics are determined by carrier type and mobility
- Normalize thermal conductivity κ
- p-FET to n-diffusion
 - Thermal conductivity is dominated by body



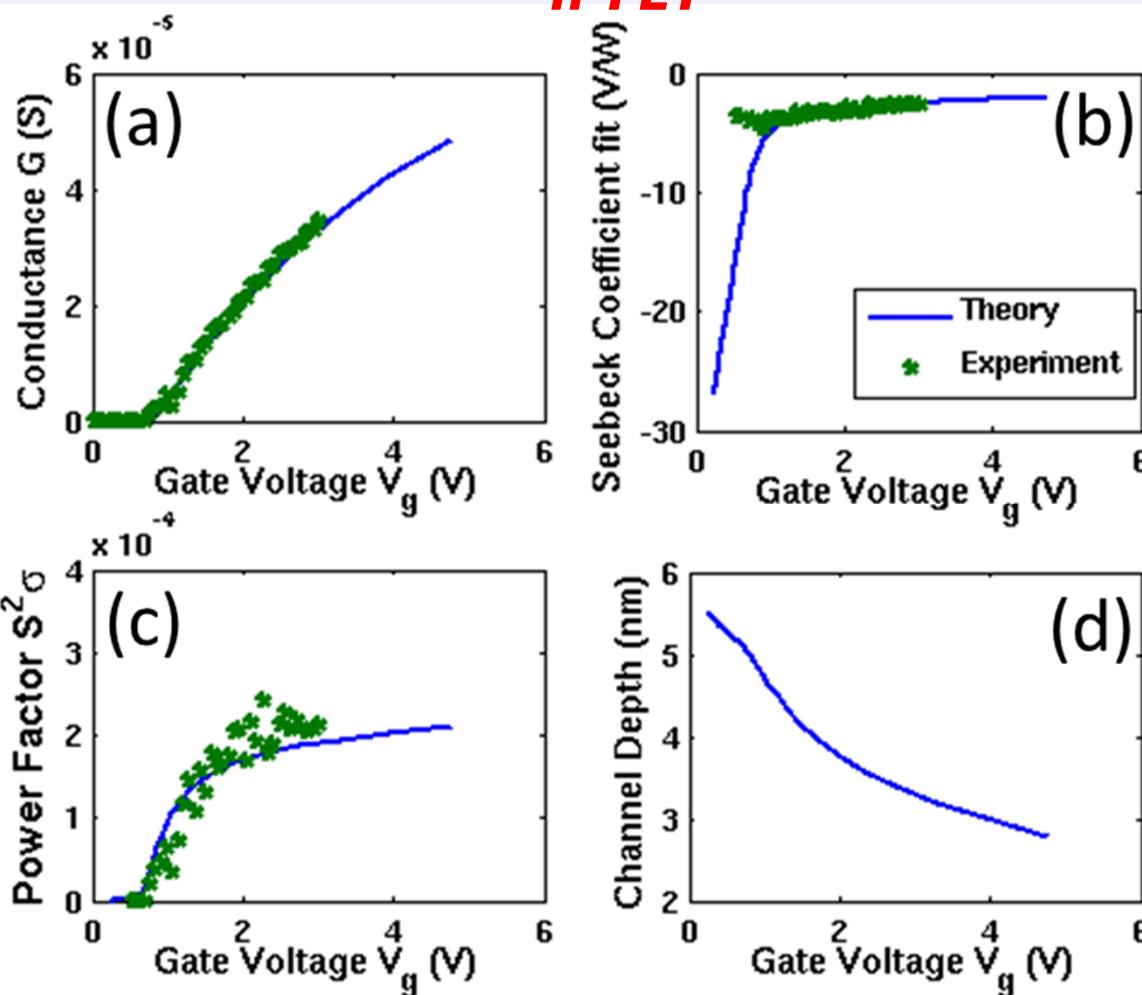
Electric Measurements:



Theory Versus Experiment

How Does the theory Compare with the Experiment?

n-FET

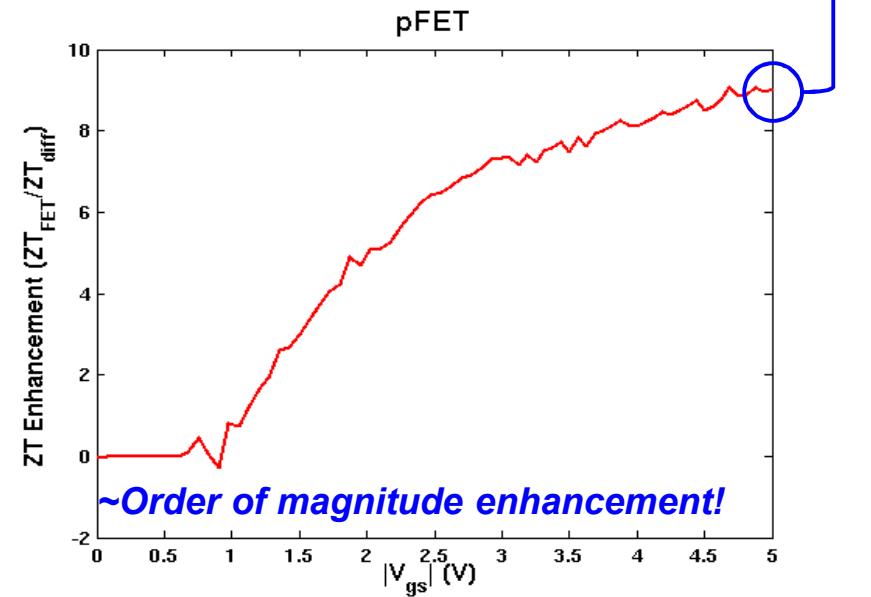
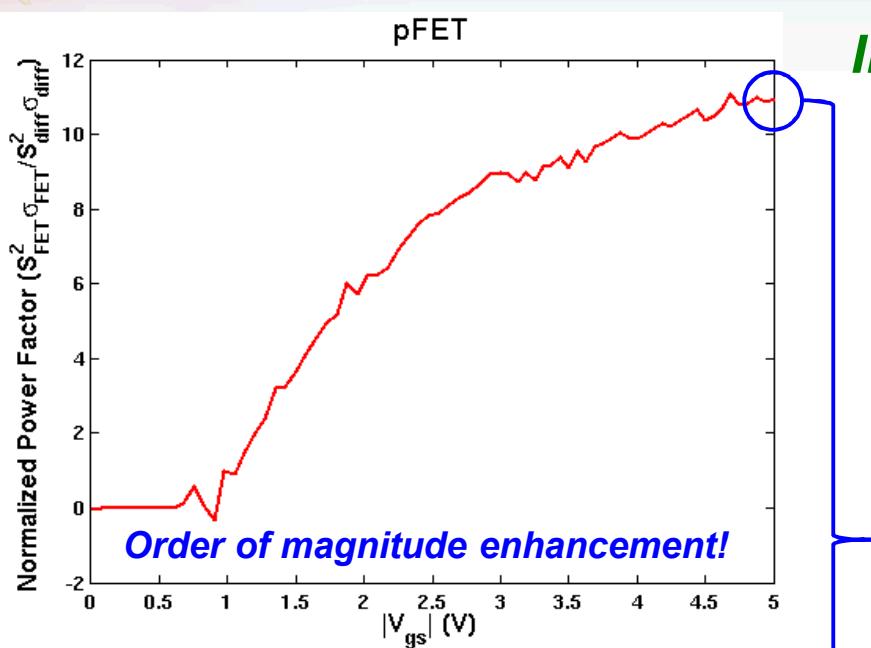


Caveat:

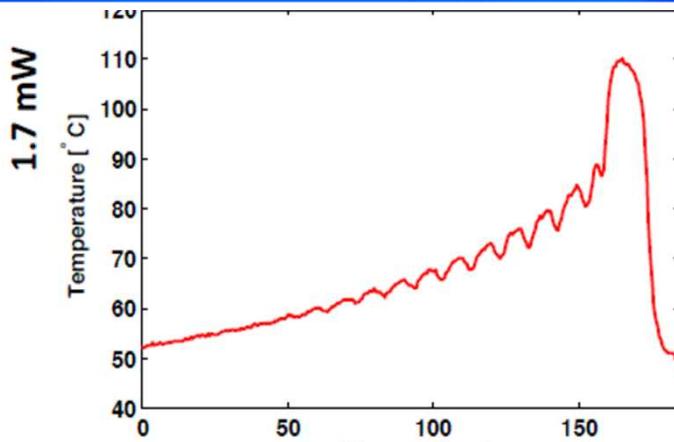
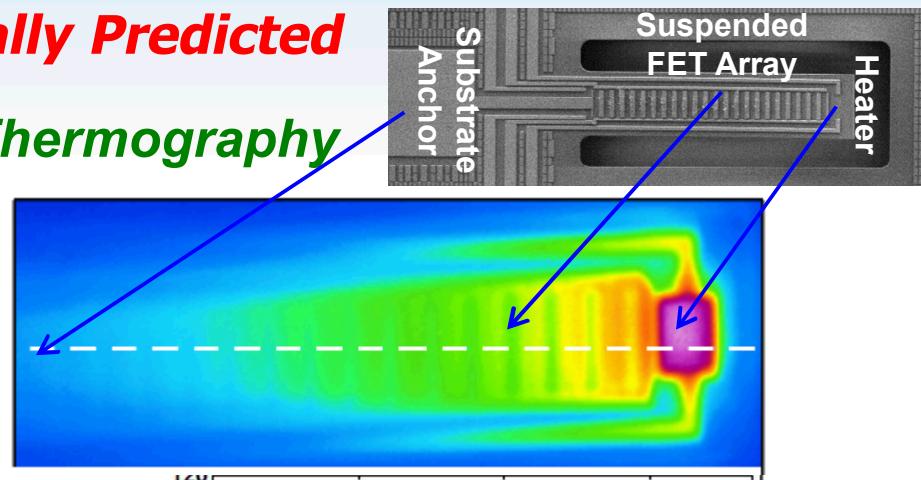
- Qualitative agreement only at this point
- Don't have exact doping numbers
- Values scaled until match was found

ZT & Power Factor

Experimentally Predicted



IR-Thermography



Quantitative Measurements:

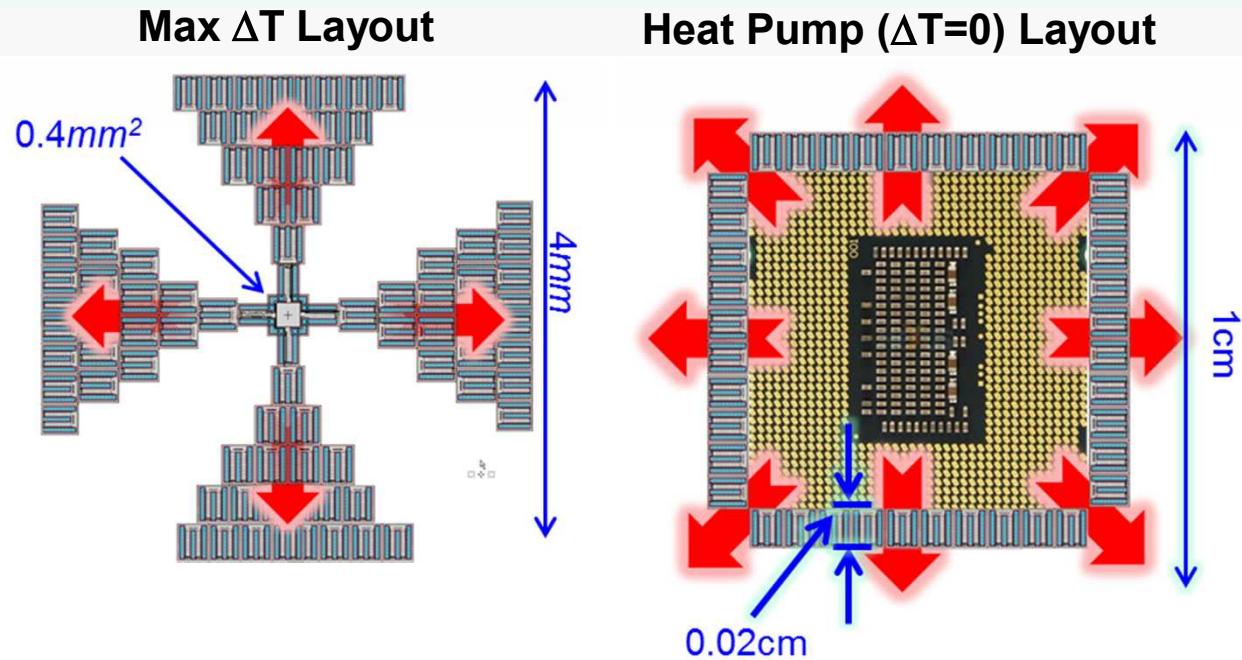
- 250nm SOI Si-CMOS7
- $S_{QC} = 400 \mu\text{V/K}$
- $\kappa = 40 \text{ W/mK}$
- $\sigma = 5.74 \times 10^4 \text{ S/m}$
- $ZT_{room} = 0.08 \leftrightarrow ZT_{Si\text{-max}} \sim 0.008!$
- No wafer thinning yet!

Potential Designs

Possible Temp Control and Cooling Demos

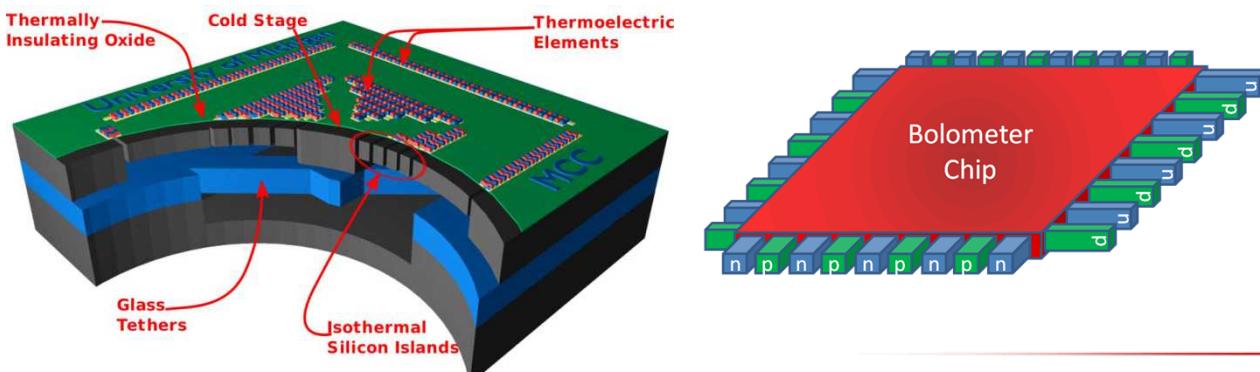
Ongoing Demo Circuits for T ($\Delta T=0$) Control:

- *Resistor Element*
- *Single Diode*
- *Band Pass filter (RC circuit)*
- *Bandgap Reference circuit*
- *Balanced Differential Amplifier circuit*



Potential Applications:

- *Precise T control of islands for memristor applications, e.g. Vanadium Oxide*
- *Uniform T or constant ΔT across a ROIC*
- *Chip Cooling*
- *Energy Generation and Scavenging*





Summary & Conclusions

- Measured data confirms QC effects
- **Non classical** TE behavior observed for first time!
- Observed **order of magnitude enhancement** in Power Factor
- Observed \sim **order of magnitude enhancement** in ZT
- The realization of a new class of TE devices in CMOS compatible platforms including for the **first time** Si-based TE devices enabling monolithic integration of TE coolers and scavengers.
- **First direct demonstration** of deterministic engineering and optimization of the Seebeck coefficient in a semiconductor material.